

H-811

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

N. KOFUJI et al

Serial No. 09/363,191

Group Art Unit: 1765

Filed: July 29, 1999

Examiner: V. Perez-Ramos

For: DRY ETCHING APPARATUS AND A METHOD OF
MANUFACTURING A SEMICONDUCTOR DEVICE

RESPONSE TO RESTRICTION REQUIREMENT

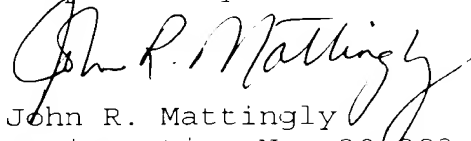
Commissioner of Patents
Washington, D.C. 20231

Sir:

In response to the Restriction Requirement mailed
November 6, 2000, applicants elect Group I, Claims 1-20, drawn
to an etching apparatus, without traverse.

The Commission is hereby authorized to charge any fees
due in connection with this response to Deposit Account No.
50-1417.

Respectfully submitted,


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